

**INFORMATION DISCLOSURE CITATION**  
(Use several sheets if necessary)

Docket Number (Optional)

TWI-31500

Application Number

09/938,415

Applicant(s)

Kenneth C. Johnson et al.

Filing Date

August 23, 2001

Group Art Unit

2851

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
AS	AA	5,867,276	02/02/1999	McNeil et al.	356	445	03/07/1997
AS	AB	5,963,329	10/05/1999	Conrad et al.	356	372	10/31/1997

**FOREIGN PATENT DOCUMENTS**

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

**OTHER DOCUMENTS**

(Including Author, Title, Date, Pertinent Pages, Etc.)

AS	AC	J. Allgair et al., "Manufacturing Considerations for Implementation of Scatterometry for Process Monitoring," <i>In Metrology, Inspection, and Process Control for Microlithography XIV, Proceedings of SPIE</i> , Vol. 3998 (2000), pp. 135-134.					
AS	AD	J. Bao et al., "Specular Spectral Profilometry on Metal Layers," <i>In Metrology, Inspection, and Process Control for Microlithography XIV, Proceedings of SPIE</i> , Vol. 3998 (2000), pp. 882-892.					

Examiner

Date Considered

Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.